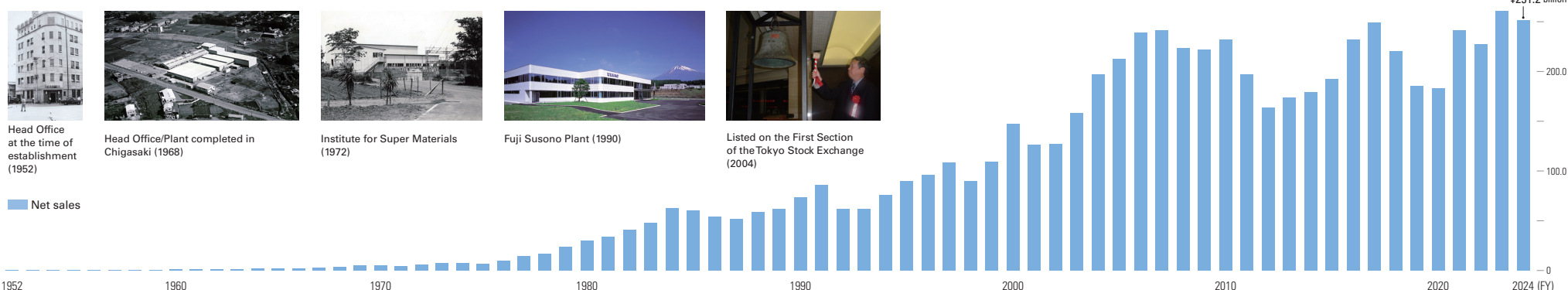


ULVAC's History

Ever since its foundation in 1952, ULVAC has been contributing to the resolution of social issues in each successive era by deploying its core state-of-the-art vacuum technology, and has grown remarkably.

ULVAC will continue contributing to the development of industry and science through the comprehensive application of vacuum technology in accordance with the Basic Corporate Philosophy.



1952-1970 High economic growth period

Industrial restoration and convenience in daily life

Applied vacuum equipment to contribute to industries supporting people's lives

- 1952 Japan Vacuum Engineering Co., Ltd. was founded.
- 1955 Opened the Omori Plant in Tokyo to start manufacturing equipment in Japan.
- 1959 Opened the Yokohama Plant.
- 1964 Established the first overseas subsidiary in Hong Kong.
- 1968 Head Office/Plant completed in Chigasaki, Kanagawa Prefecture.

Contribution to resolution of social issues

- Developed vacuum arc furnaces for stainless steel and other steel manufacturers, contributing to industrial restoration.
- Developed vacuum melting and casting furnace for nuclear power development, contributing to the solution of energy problems.
- Developed highly sensitive vacuum gas analysis for direct analysis of air pollution.
- Delivered a large-scale space chamber to the space research lab at the University of Tokyo, contributing to space development.
- Developed vacuum freeze-drying equipment for instant foods, contributing to the improvement of food culture.

1971-1990 Development of electronics

Comfortable working environment

In line with increasing demand for semiconductors, a stream of ULVAC products gained top shares in the global market.

- 1972 Opened the Institute for Super Materials as ULVAC's first research facility.
- 1975 Established a subsidiary in North America as a base for exports to the U.S.
- 1982 Established a subsidiary in Taiwan.
- 1983 Opened the Beijing Office in China.
- 1990 Opened the Fuji Susono Plant in Shizuoka Prefecture, as a plant dedicated to semiconductor production equipment.

Contribution to resolution of social issues

- Delivered vacuum pumping system for a critical plasma tester to Japan Atomic Energy Research Institute.
- Developed transparent conductive film deposition equipment for LCDs for calculators.
- Developed the world's first multi-chamber deposition system for semiconductor memory.
- Delivered the world's first computer-controlled vacuum deposition system for semiconductors to IBM.
- Developed sputtering equipment for hard disk deposition, making a significant contribution to improvement of computer performance.

1991-2010 Information society, spread of digital home appliances

High-performance devices

ULVAC grew significantly in line with the expansion of the FPD market from Japan to South Korea and Taiwan.

- 2001 Changed the company name to ULVAC, Inc.
- 2003 Established a full-scale production and service base in China.
- 2004 Listed on the First Section of the Tokyo Stock Exchange. New buildings of the Head Office/Plant (Chigasaki) completed.
- 2005 Opened the ChibaTomisato Plant for the development and manufacturing of materials.

Contribution to resolution of social issues

- Developed the CERAUS series of multi-chamber deposition systems for semiconductors.
- Developed the SMD series of sputtering systems for LCDs, contributing to mass production of laptop PCs. It subsequently became the foundation for the popularization of flat-screen TVs.
- Developed deposition equipment for OLED, which is a next-generation display.
- Developed ion implantation system for mass production of power devices that contribute to power saving.
- Developed the ECO-SHOCK power-saving attachment for dry pumps.
- Developed an integrated production line for thin-film solar cells to meet the demand for renewable energy.

2011-Present Digital society

Sustainable future

Contributing to a wide range of fields by leveraging strengths as a comprehensive vacuum equipment manufacturer

- 2018 Opened the ULVAC-Osaka University Joint Research Laboratory for Future Technology at Osaka University.
- 2021 Opened the ULVAC Advanced Technology Collaborative Research Cluster at Tokyo Institute of Technology (now Institute of Science Tokyo).
- 2022 Listed on the Prime Market of the Tokyo Stock Exchange.
- 2024 Established Technology Center PYEONGTAEK in South Korea

Contribution to resolution of social issues

- Development of thin-film lithium metal anode using vacuum deposition technology was selected for the NEDO* Green Innovation Fund Project "Development of Next-Generation Storage Batteries and Next-Generation Motors."
- The ULVAC-Osaka University Joint Research Laboratory for Future Technology at Osaka University is conducting basic research in the regenerative medicine and energy fields and accepts students for Japan's first corporate co-creation program.
- The ULVAC Advanced Technology Collaborative Research Cluster at the Institute of Science Tokyo aims at co-creation, such as human resources development and integration of plasma diagnostics technology and AI technology.
- Developed extreme ultraviolet (EUV) lithography-ready sputtering equipment for Metal Hard Mask (MHM) process, contributing to mass production of high-speed, low-power-consumption advanced logic devices.

* New Energy and Industrial Technology Development Organization